AMENDMENTS TO SPECIFICATIONS ARE AS FOLLOWS:

page 1, line 14:

the thickness variations of pad oxide, which may be in the range of 30-50 °A Å, the long channel

page 5, line 12, line 13, and line 15:

approximately about $25 - 120^{\circ} A \stackrel{A}{\underline{A}}$ thick and pad nitride 14 in the range of approximately about

500 – 2000 °A A thick; using a plasma process, pattern the pad nitride using a resist mask; using

... shallow trench, in the range of approximately about 2000-5000 ^{6}A ^{6}A using suitable plasma ...

page 6, line 12:

implantation is shown in Figure 4 for two pad oxide thicknesses of 50 and 100 °A A. It is clear ...

page 7, line 5 and line 10:

variation for pad oxide thickness variation in the range of $35 - 110^{\circ}$ A $\frac{\mathring{A}}{10}$ is 0.489 + -0.0327 volts

Pad Oxide Thickness, ${}^{\theta}$ **A** Å 110 100 90 80 70 60 35 0

page 8, line 3:

 ${}^{\theta}A$ $\underline{\mathring{A}}$ of equivalent silicon dioxide thickness.